This Sheet Has Been Replaced

ABSTRACT

A wafer transport module [10] interconnects a horizontal wafer handler [11] with a vertical wafer processor [12] and includes an evacuatable housing [26] with a first port [36] in communication with the horizontal wafer handler [11] and sized to permit passage of a wafer [35] therethrough in horizontal orientation and a second port [38] in communication with a load/unload station of the vertical wafer processor [12] and sized to permit passage of wafers [35] therethrough in vertical orientation. The transport module [10] includes a wafer holder [25] which supports a wafer [35] on a pedestal [52] and rotates the pedestal [52] and wafer [35] about an inclined axis [28] between horizontal orientation adjacent the first port [36] and vertical orientation adjacent and in alignment with the second port [38]. The wafer holder [25] horizontally extends the vertically oriented platen [52] and wafer [35] from the second position through the second port [38] to the load/unload station of the vertical processor [12]. After wafer processing, the sequence is reversed to return the wafer [35] to the horizontal wafer handler [11].